



Attorney Docket No.:029368.50324US
PATENT

Image
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: SHINCHIRO YAGI
Serial No.: 09/914,044 Group Art Unit: 2851
Filed: DECEMBER 11, 2001 Examiner: Fuller, Rodney Evan
Title: INSPECTION OBJECT SILICON WAFER FOR THE PURPOSE
OF DETECTING CRYSTAL DEFECTS AND THE METHOD OF
DETECTING THEREOF

REPLY TO OFFICE ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This is in response to the Office Action mailed July 8, 2003.

This reply is accompanied by a Petition under 37 CFR §1.136(a) for a one-month extension of time and by a check in the amount of \$110.00 in payment of the required extension fee.

Kindly amend the application as follows: